

# Resource Summary Report

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## UConn Nanofabrication Facility

RRID:SCR\_012346

Type: Tool

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### Proper Citation

UConn Nanofabrication Facility (RRID:SCR\_012346)

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### Resource Information

**URL:** <http://www.scienceexchange.com/facilities/nanofabrication-facility>

**Proper Citation:** UConn Nanofabrication Facility (RRID:SCR\_012346)

**Description:** THIS RESOURCE IS NO LONGER IN SERVICE. Documented on May 16, 20224. Nanofabrication Facility houses three instruments for patterning of flat surfaces and selective etching of materials. Researchers fabricate devices and structures to demonstrate novel device concepts and to characterize new materials. To carry out these functions this new facility consists of three instruments: a Tescan Electron-Beam Lithography Tool, an OAI high resolution Mask Aligner and Advanced Vacuum/Plasma Therm Reactive Ion Etcher.

**Abbreviations:** UConn Nanofabrication Facility

**Synonyms:** UConn Biotechnology - Bioservices Center Nanofabrication Facility, University of Connecticut Biotechnology - Bioservices Center Nanofabrication Facility

**Resource Type:** access service resource, service resource, core facility

**Keywords:** electron beam lithography, optical lithography, reactive ion etching

**Availability:** THIS RESOURCE IS NO LONGER IN SERVICE

**Resource Name:** UConn Nanofabrication Facility

**Resource ID:** SCR\_012346

**Alternate IDs:** SciEx\_11967

**Record Creation Time:** 20220129T080309+0000

**Record Last Update:** 20260806T054543+0000

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### Ratings and Alerts

No rating or validation information has been found for UConn Nanofabrication Facility.

No alerts have been found for UConn Nanofabrication Facility.

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## Data and Source Information

**Source:** [SciCrunch Registry](#)

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## Usage and Citation Metrics

We have not found any literature mentions for this resource.